

1.4:

At 300 K, $E_g(\text{GaAs}) = 1.424 \text{ eV}$ and $E_g(\text{Al}_{0.2}\text{Ga}_{0.8}\text{As}) = 1.673 \text{ eV}$ (from Table 1.1).

Assume that the conduction band offset is roughly 2/3 of the energy gap difference (see p.10): $V_0 = 166 \text{ meV}$.

Approximate the electron effective mass as the effective mass of the electrons in GaAs ($= 0.067m_0$ by Table 1.1).

From Appendix 1:

$$E_1^\infty = 2.76 \left(\frac{1}{0.067} \right) \left(\frac{100 \text{ \AA}}{100 \text{ \AA}} \right) = 56.1 \text{ meV} \quad (\text{A1.14})$$

By Eq. A1.17

$$\begin{aligned} n_{\max} &= \sqrt{\frac{V_0}{E_1}} \\ &= \sqrt{\frac{166 \text{ meV}}{56.1 \text{ meV}}} \\ &= 1.72 \end{aligned}$$

a) There are two bound states since $1 \leq n_{\max} < 2$.

b) Using Figure A1.4, find the quantum numbers:

$$n_{QW_1} = 0.724$$

$$n_{QW_2} = 1.397$$

$$E_n = n_{QW}^2 E_1$$

$$E_1 = 29.4 \text{ meV}$$

$$E_2 = 109 \text{ meV}$$

1.6:

a)

$$E = E_1 + 2\Delta E \cos(ka) \quad (A1.27)$$

$$\Delta E = 0.2 \text{ eV}$$

$$a = 0.3 \text{ nm}$$

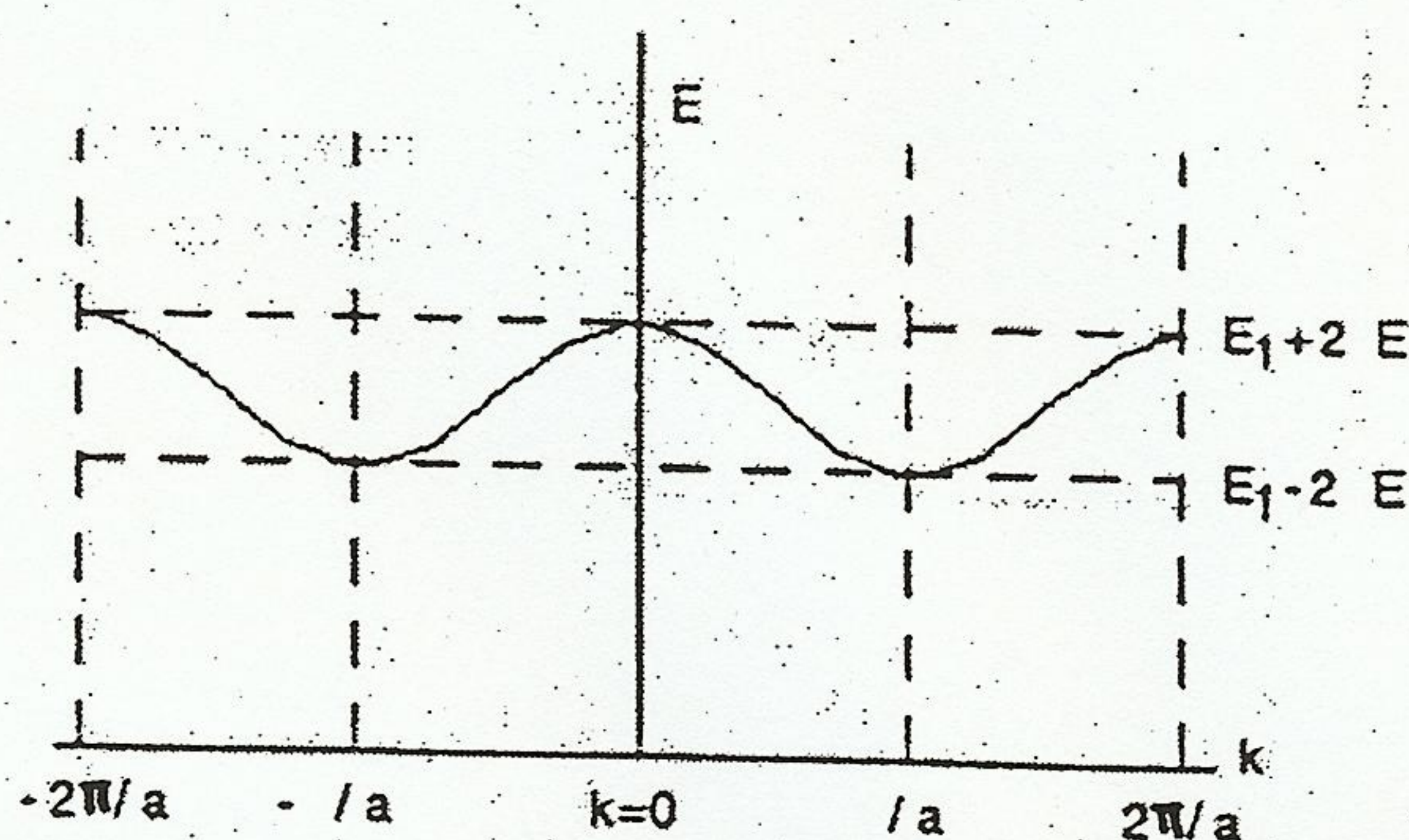


Figure 1.6a. Energy band over the first two Brillouin zones ($-\frac{2\pi}{a} \leq k \leq \frac{2\pi}{a}$)

b)

$$m^* = \hbar^2 \left(\frac{\delta^2 E}{\delta k^2} \right)^{-1}$$

$$= \hbar^2 \left(\frac{\delta}{\delta k} \frac{\delta}{\delta k} (E_1 + 2\Delta E \cos(ka)) \right)^{-1}$$

$$= \frac{-\hbar^2}{2\Delta E a^2 \cos(ka)}$$

For a minimum of the energy band, $\cos(ka) = -1$ $m^* > 0$.

For a maximum of the energy band, $\cos(ka) = +1$ $m^* < 0$.

$$\frac{m^*}{m_0} = \pm \frac{\hbar^2}{2\Delta E a^2 m_0}$$

$$= \pm \frac{(6.59 \times 10^{-16} \text{ eV s})^2 (3 \times 10^{10} \frac{\text{cm}}{\text{s}})^2}{2(0.2 \text{ eV})(0.3 \times 10^{-7} \text{ cm})^2 (0.511 \times 10^6 \text{ eV})}$$

$$= \pm 2.12$$

where we have used $m_0 = 0.511 \text{ meV}/c^2$.

✶ 1.7:

$$\begin{aligned}
 E_g(\text{GaAs}) &\approx 1.42 \text{ eV} \\
 \lambda_g &= \frac{1.24 \text{ eV}\mu\text{m}}{E_g} \\
 &= 873 \text{ nm}
 \end{aligned}$$

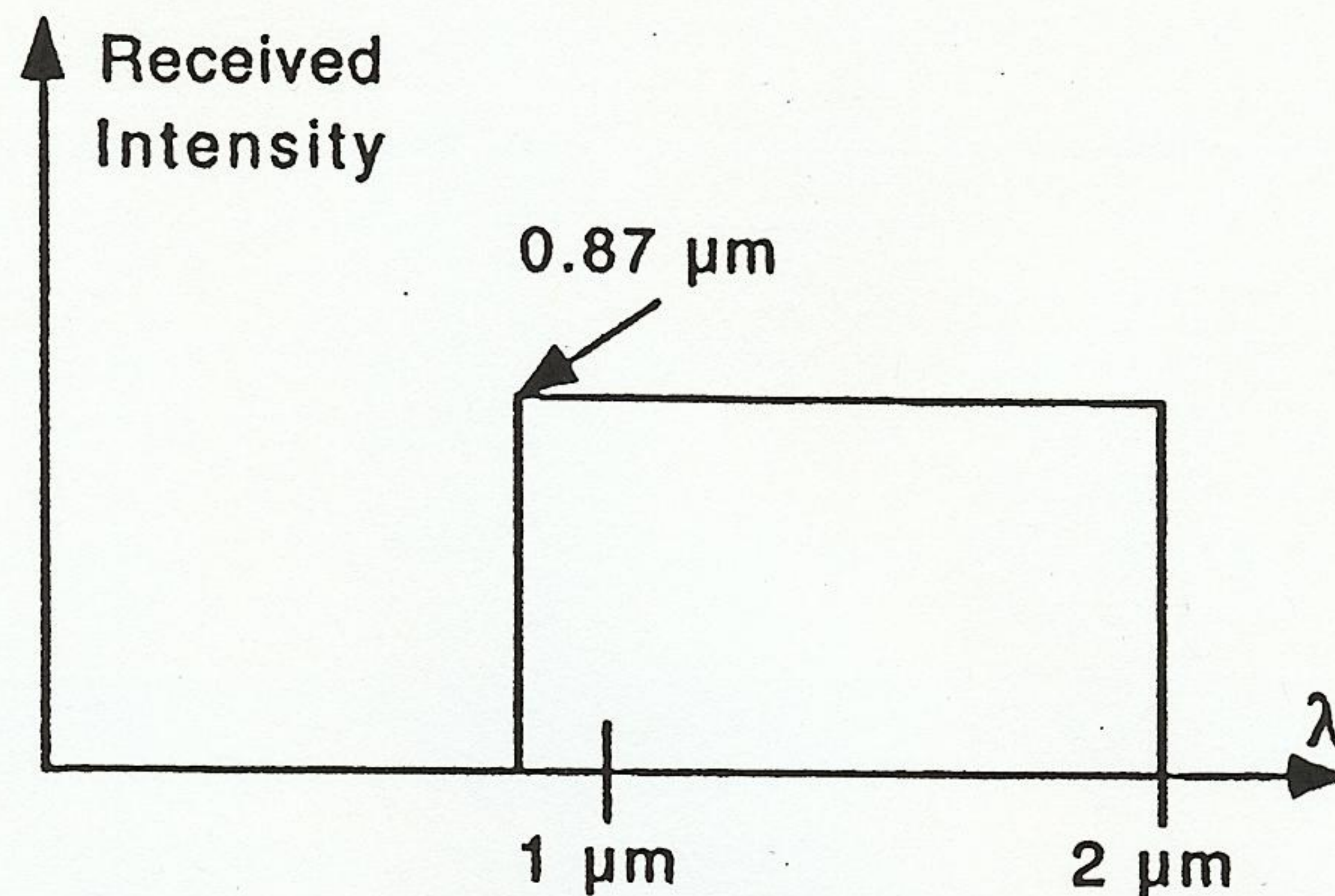


Figure 1.7. Received intensity vs. wavelength

Absorption: (R_{21})

All photons with energies greater than the bandgap (i.e. wavelengths $< 873 \text{ nm}$) will be absorbed (This assumes reasonably low powers and that the wafer is more than a few microns thick.) This process will generate electron-hole pairs in the sample.

Non-radiative Recombination: (R_{nr})

The electron-hole pairs must recombine and one way is non-radiatively. The e-h pair will recombine and dissipate energy as lattice vibration (heat).

Spontaneous and Stimulated Emission: (R_{sp} and R_{st})

Some e-h pairs will recombine and create a photon. Photons generated by both processes will be near the bandgap energy (with a thermal distribution). Measuring the peak wavelength of the light emitted from a semiconductor when it is illuminated by an above bandgap source is a good way to determine the bandgap of an unknown material.



1.8:

a) The semiconductor is being "bleached" by the Argon pump. The Argon laser light is being absorbed and this is generating e-h pairs. If the e-h pairs are being generated at a fast enough rate, the number of available states in the conduction band and valence band is being reduced so there aren't enough to completely absorb the GaAs laser light.

b) If the power is doubled to 6 W, the rate which e-h hole pairs are generated is not doubled: If the GaAs power is only 50% absorbed, additional power from the Argon laser will be less than fully absorbed. So 6 W will not double the e-h generation rate. Also, the recombination rate increases if more e-h pairs are present because $R_{sp} \propto np$. So to completely bleach the material, more power is needed to overcome both the decreased absorption and the increased recombination rate.